



O. Kugeler, S. Keckert, A. Prudnikava

I.FAST – 3rd Annual Meeting

16.April 2024 – Paris, France

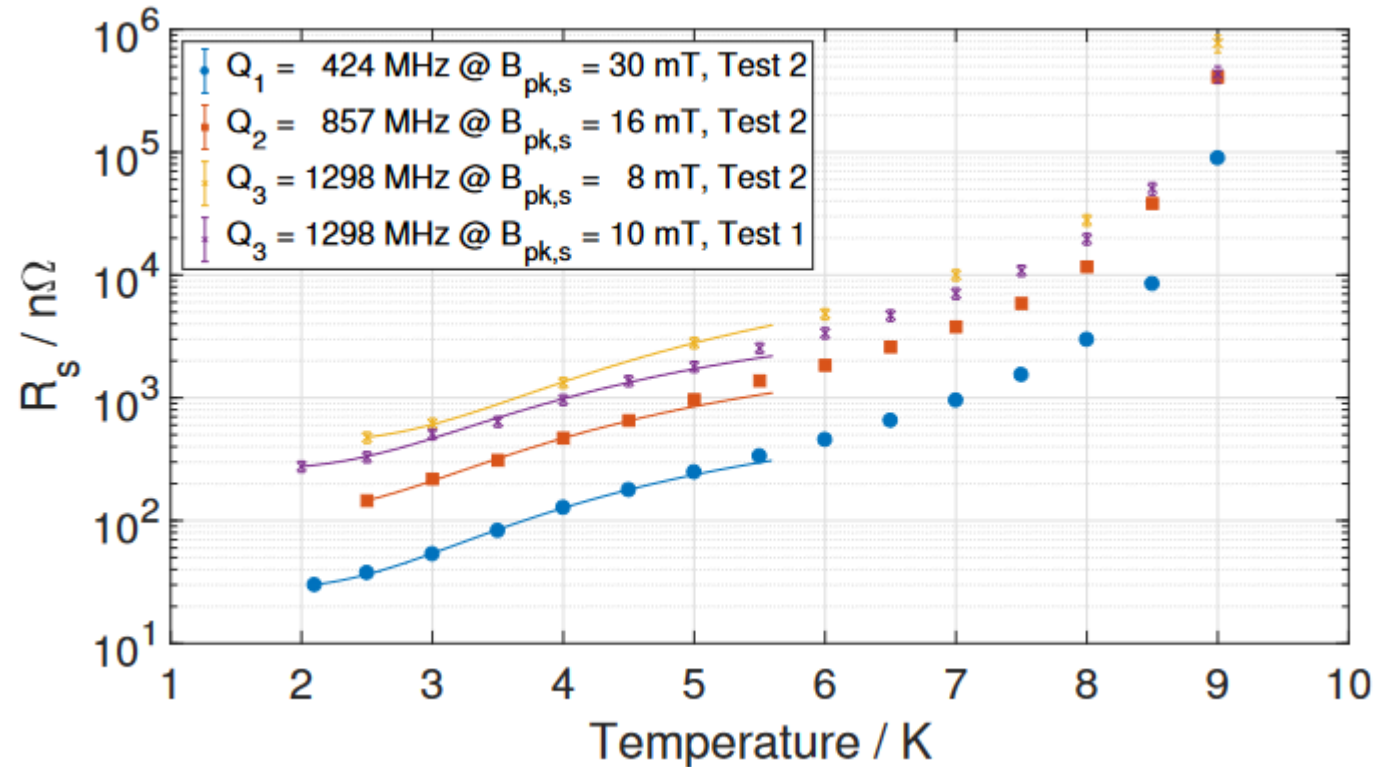
QPR status

- QPR system, network and cryo infrastructure was fixed after cyber attack
- Suffered from a 9-month halt of measurements
- 1 QPR sample measured (Nb_3Sn from Legnaro)
- 1 QPR sample in pipeline (Nb_3Sn from Daresbury) measured beginning of May
- 2 QPR samples cleaned by IJCLAB and ready for deployment

Nb₃Sn QPR from Legnaro

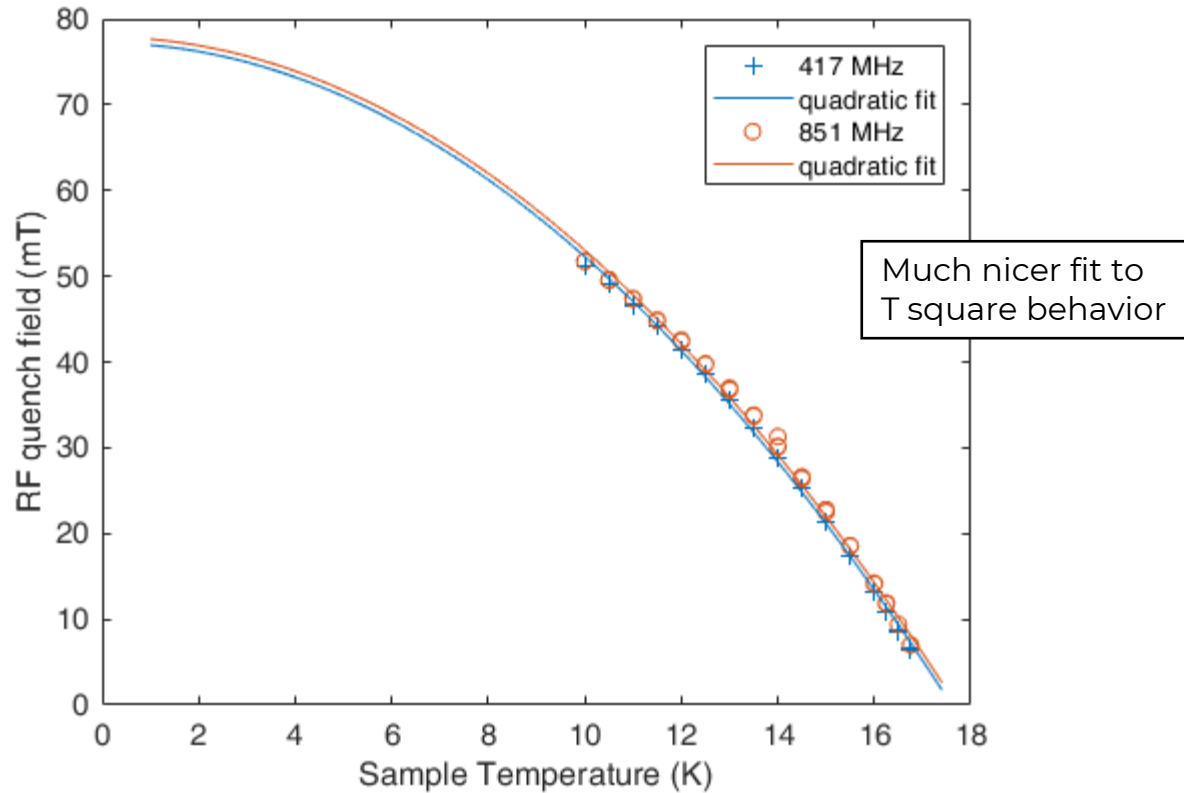
- Light BCP (10 min, 5 μm removal)
- Baking in UHV (27h, 700 °C at top of sample 870°C inside)
- Base pressure 5e-8 mbar @ 650 °C
- Nb₃Sn Coating, sputtering from stoichiometric Nb₃Sn target (approx. 1 μm, 11 h coating at 650 °C)
- Cooldown (approx. 24 h in UHV, 8e-9 mbar @ room temp)

Surface resistance measurement of substrate QPR sample



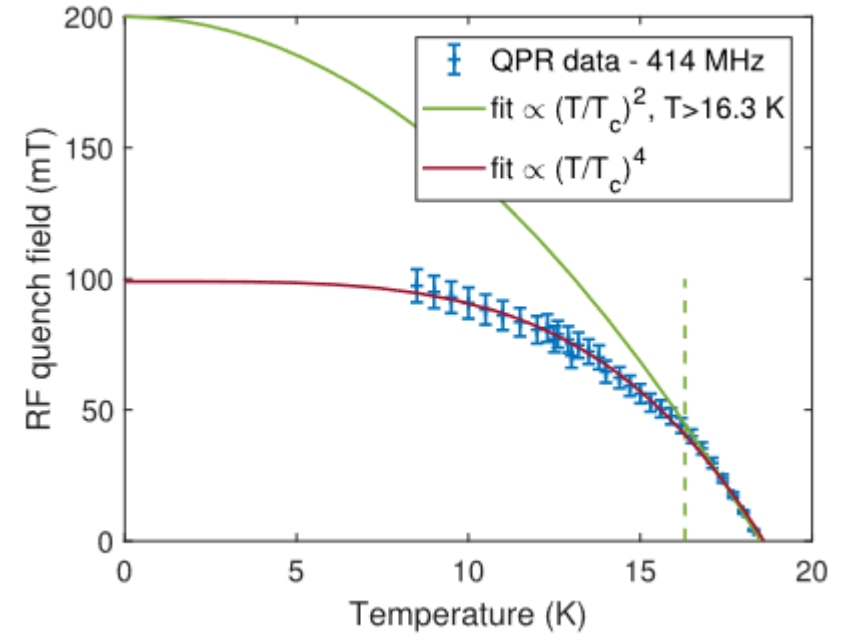
Performed by R. Monroy with Uni-HH QPR
(only for qualitative reference)

RF quench field vs T



$T_c = 17.4$ K

Fits with DC measurements on similarly produced samples

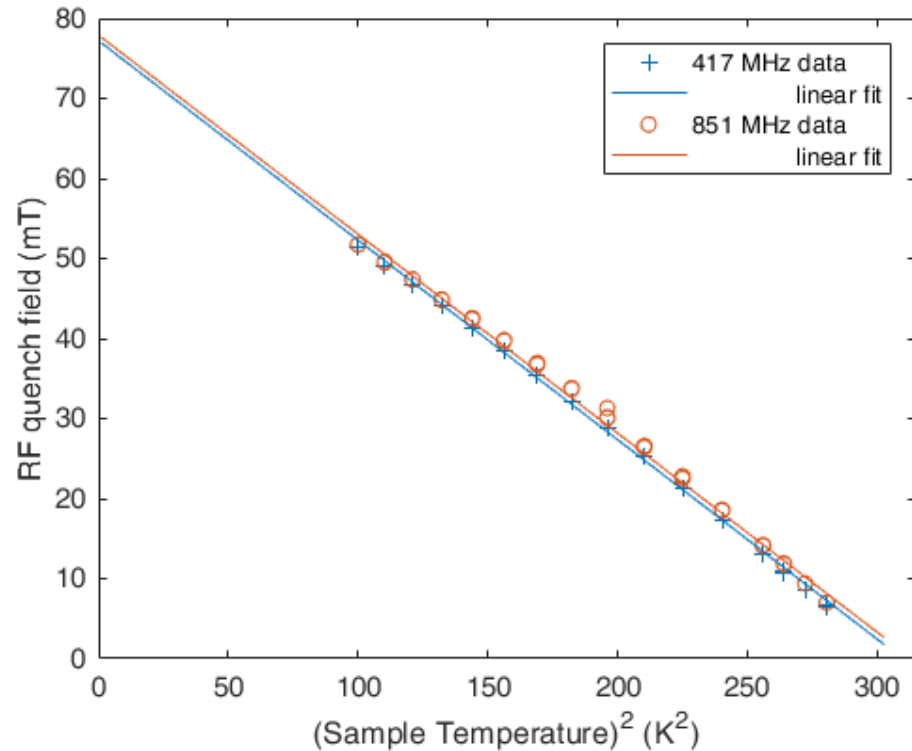


For comparison: Nb₃Sn QPR sample produced via vapor-tin diffusion by Cornell in 2017

$T_c = 18.4$ K

Room for improvement

Quench field extraction

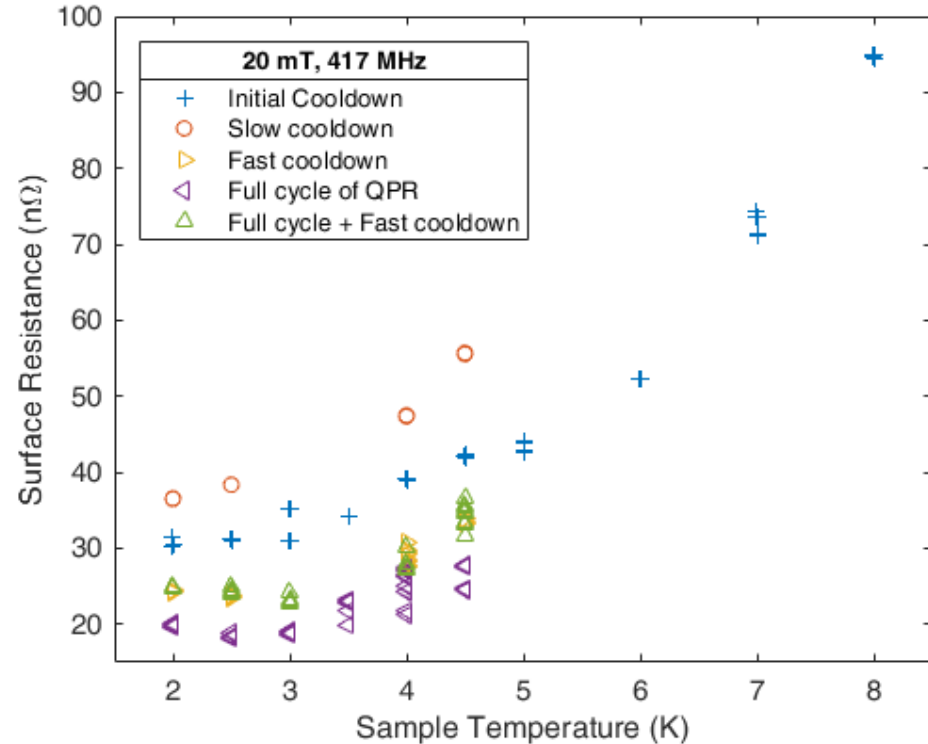


Extrapolated quench field at 0 K of 77 mT

Possibly due to reduced T_c

Room for improvement

R_s vs T



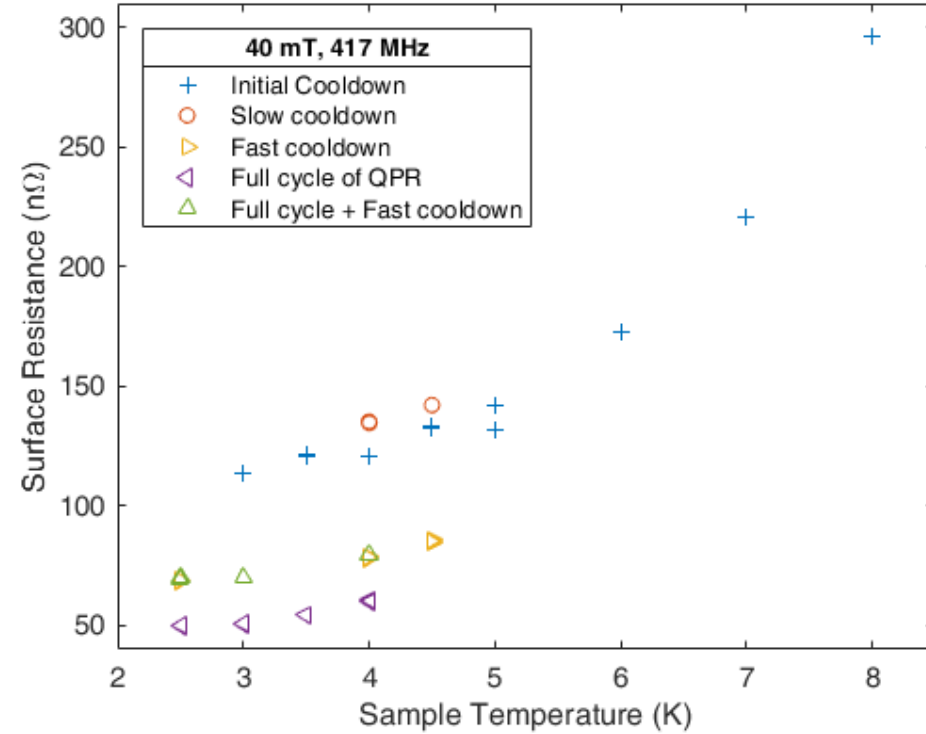
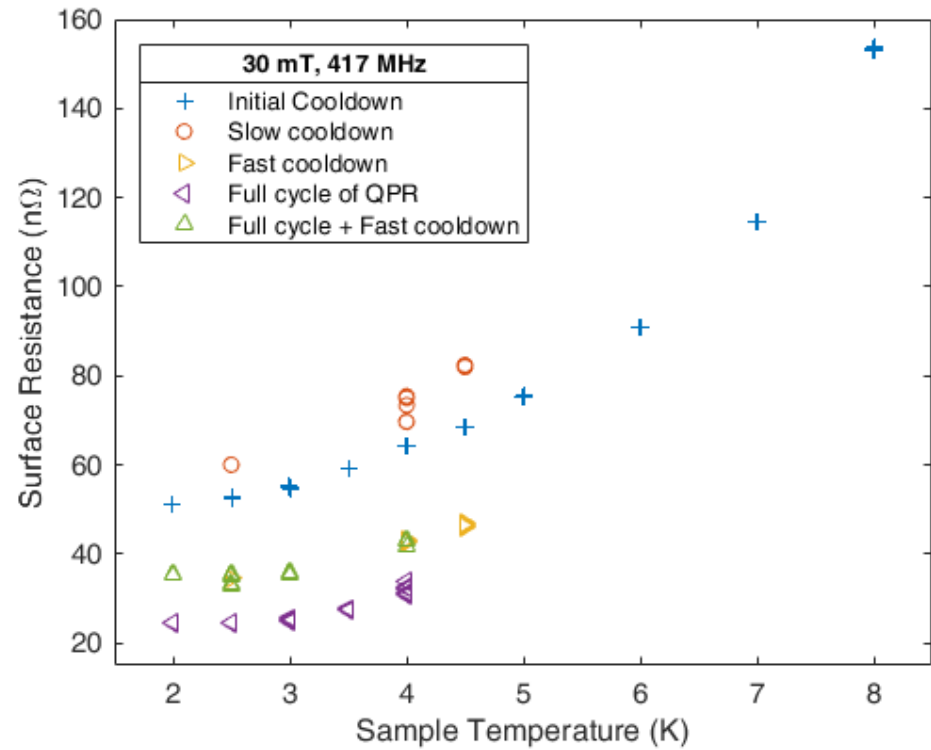
Residual resistance depends on cooling dynamics

Residual resistance of 19 nOhm measured

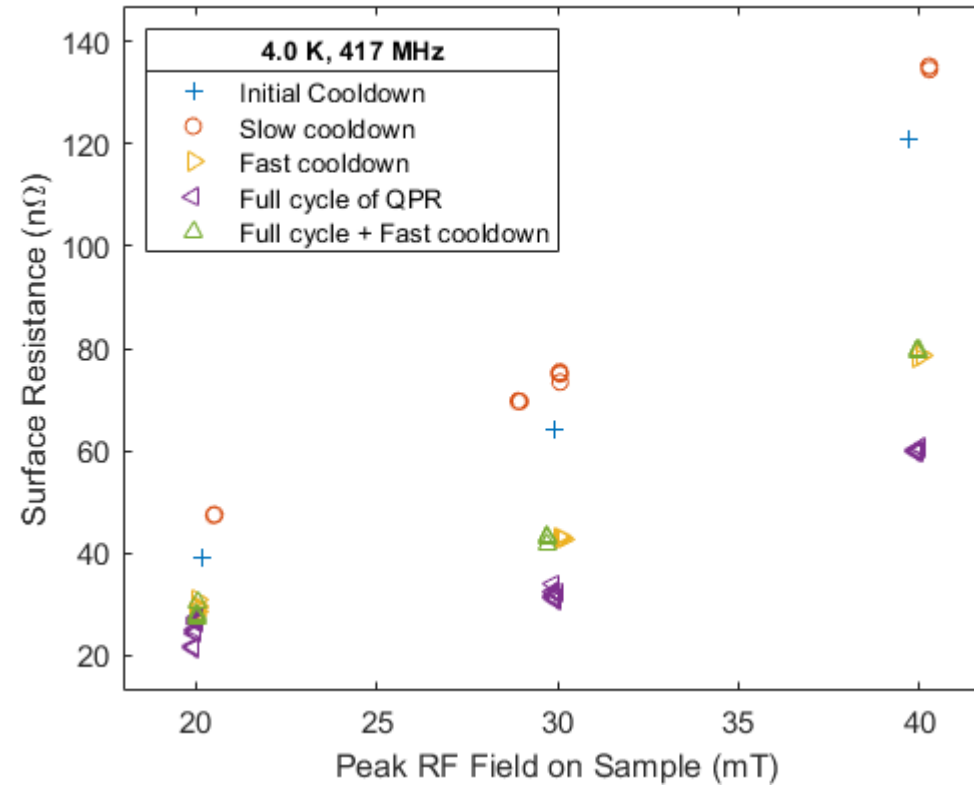
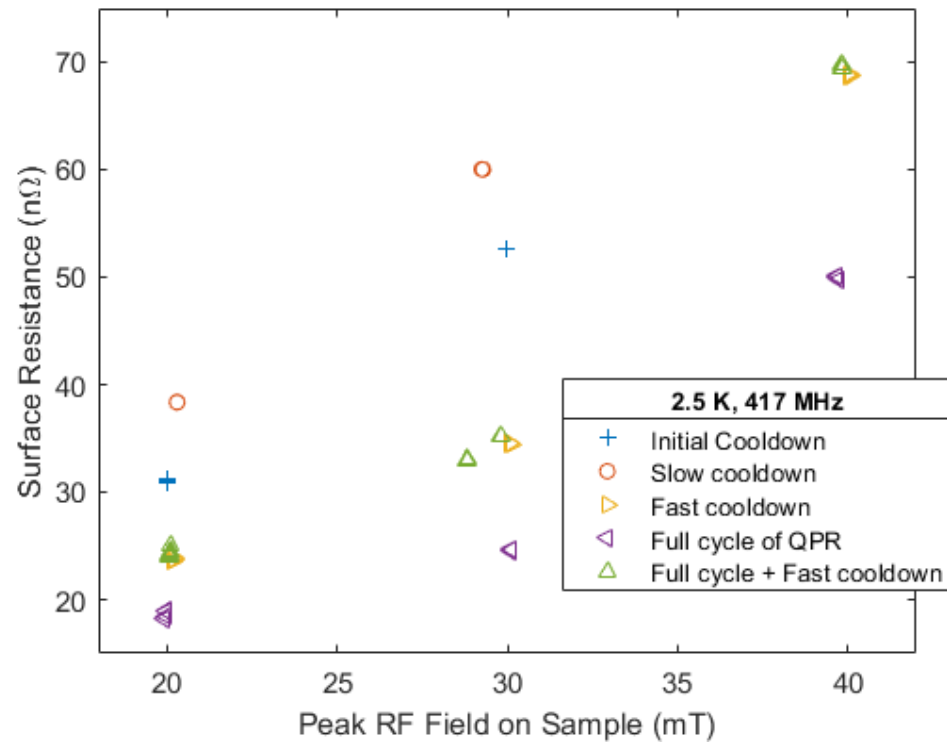
True residual resistance at optimum cooling conditions might even be lower.

Fast cooldown better than slow cooling, but spatial temperature differences should be minimized. Effects of thermal cycling in QPR different as compared to a cavity.

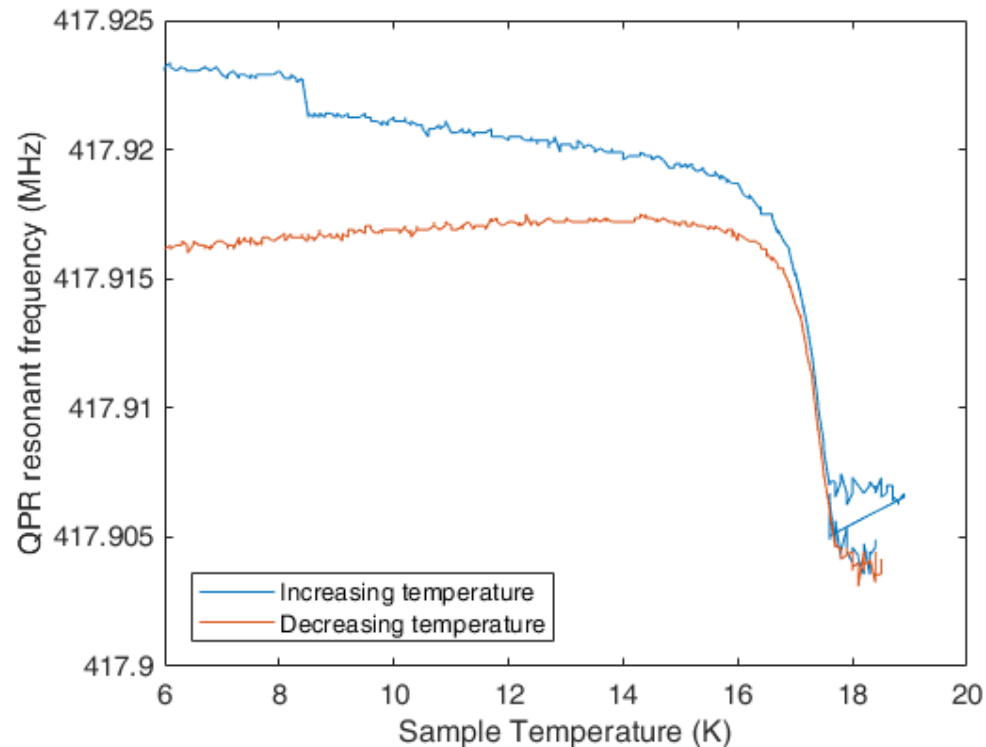
R_s vs T (at higher fields)



Rs vs B



Penetration depth



London penetration extracted from frequency change using Slater theory

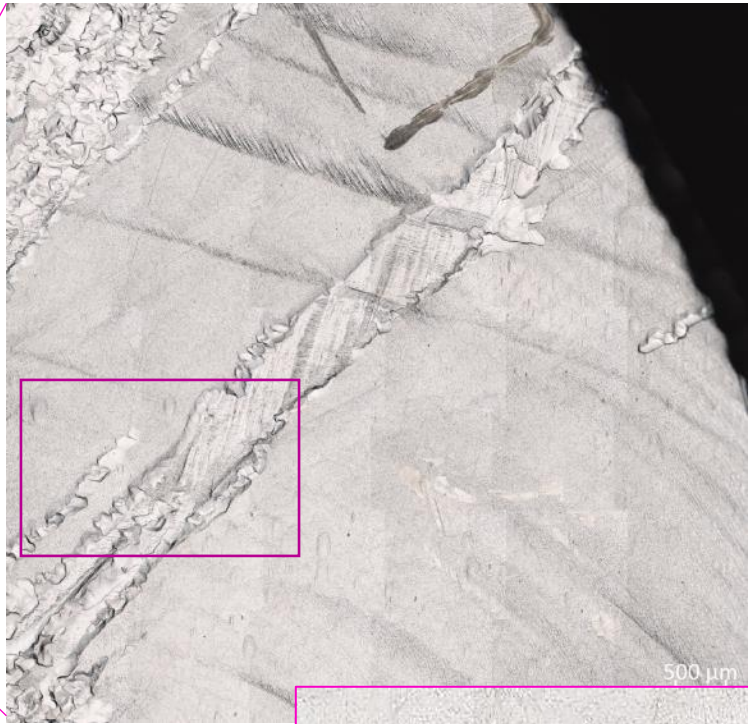
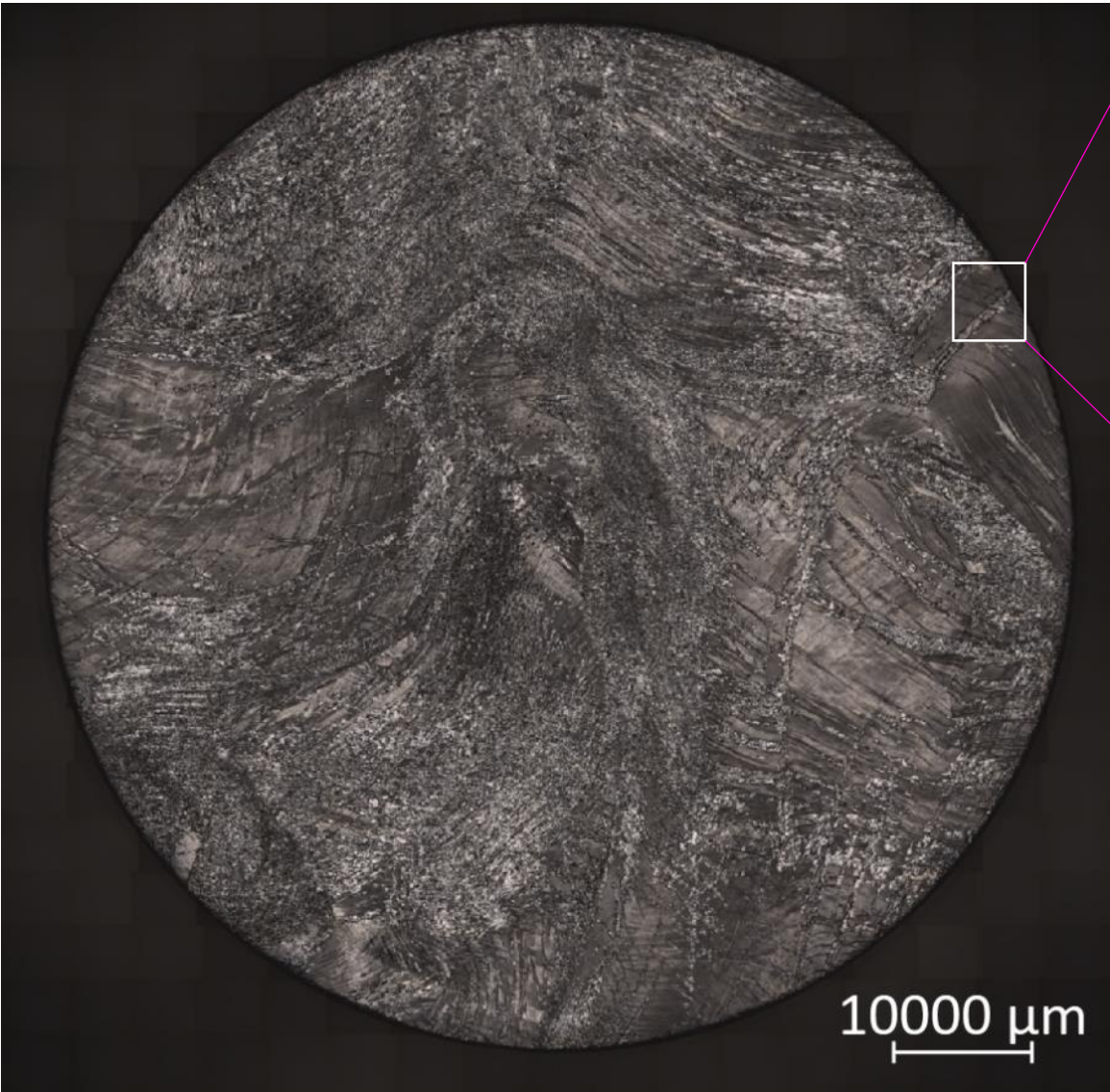
We obtain values of 350 nm (Literature value = 90 nm Cornell sample had 160 nm)

Possibly geometry factor is sensitive to surface roughness.

Need to integrate over real surface, not assumed flat surface?

$$G \sim \frac{\iiint_V |\mathbf{H}(r)|^2 dV}{\oint_A |\mathbf{H}(r)|^2 dA}$$

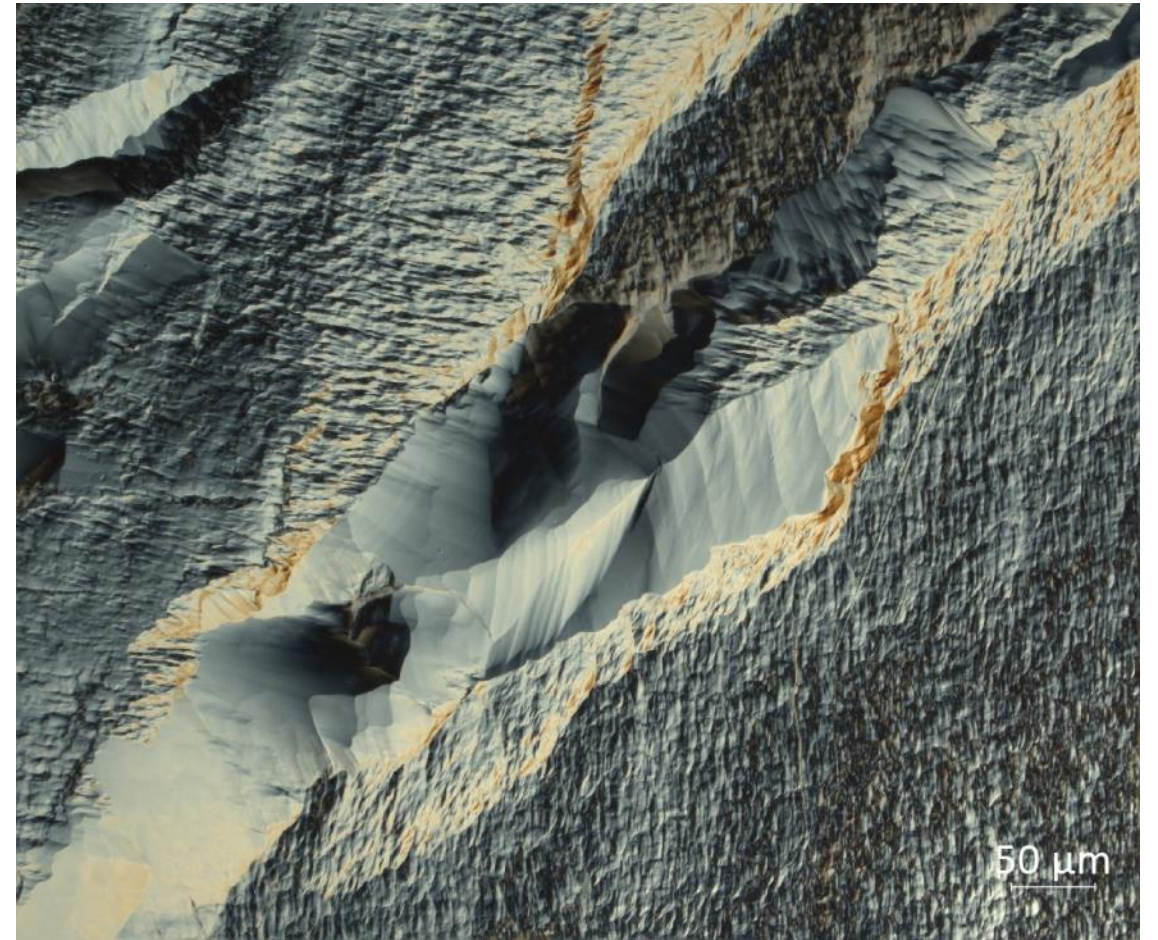
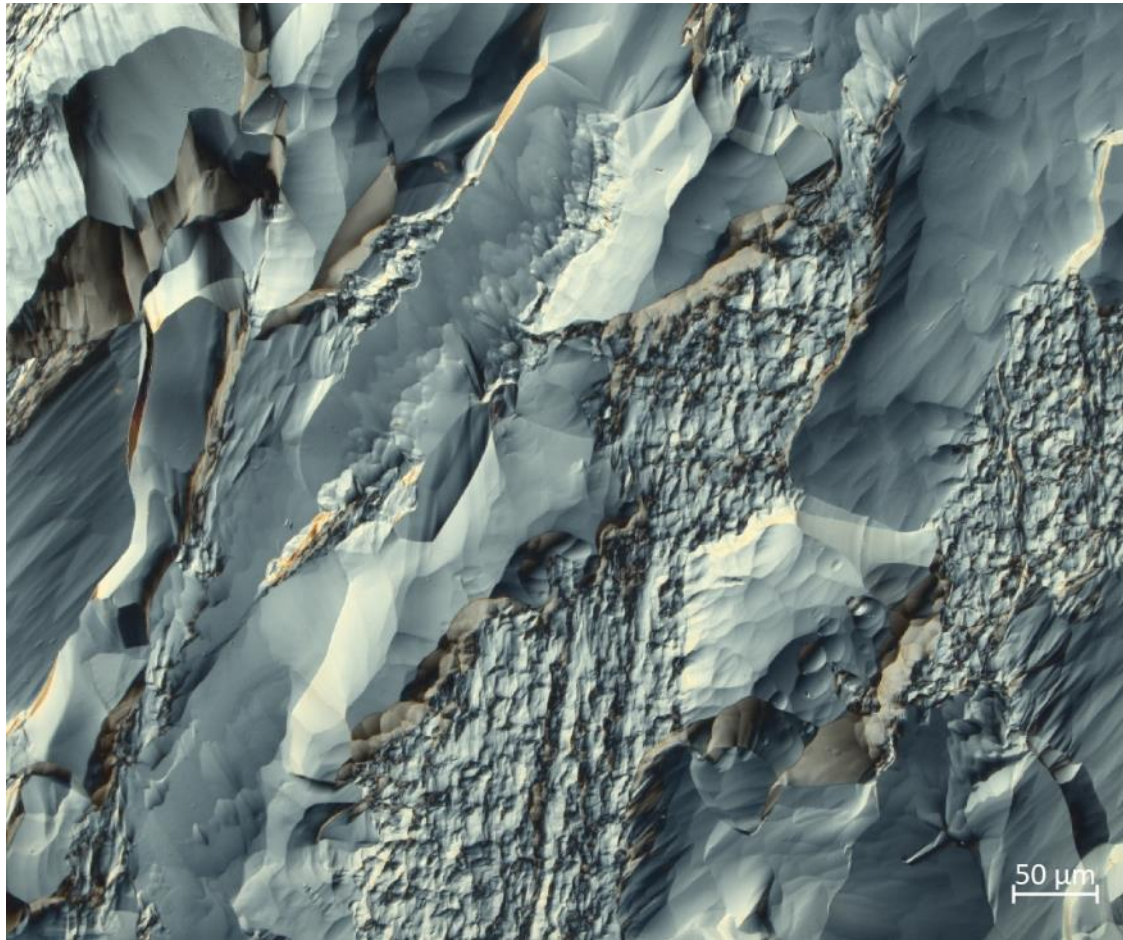
Substrate properties



Niobium QPR Sample (baseline treated at Uni Hamburg/DESY)

A. Prudnikava, BE-IAS/HZB

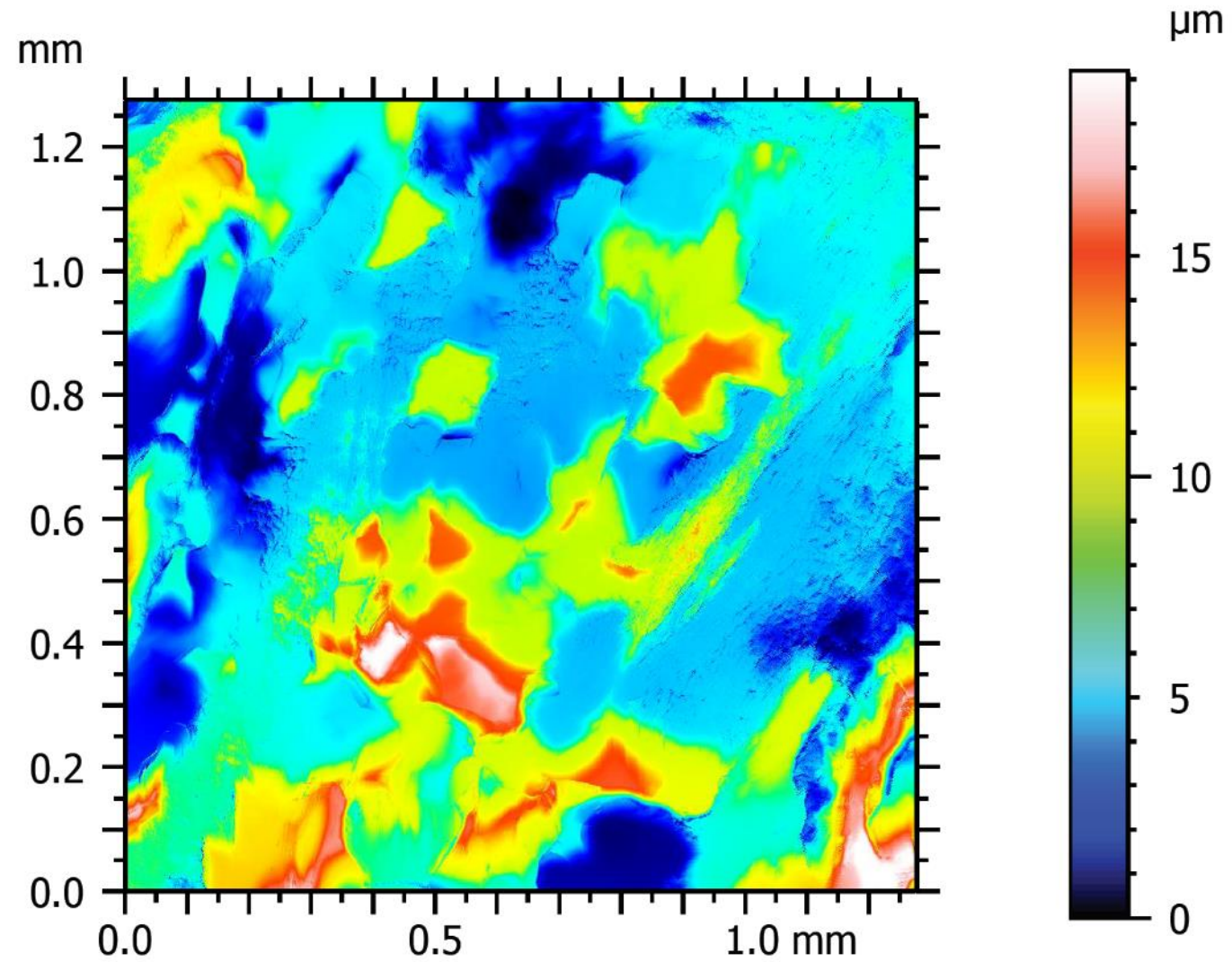
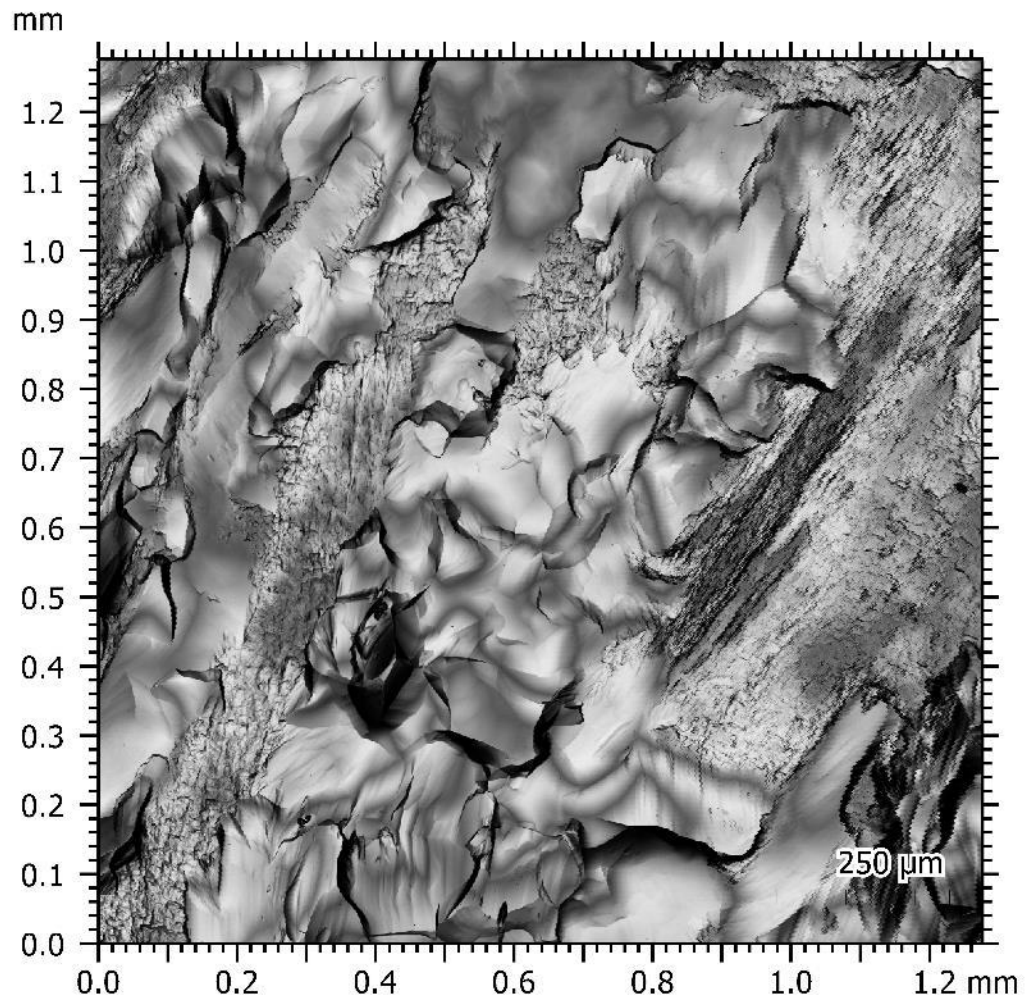
Optical (Polarized Light) Images



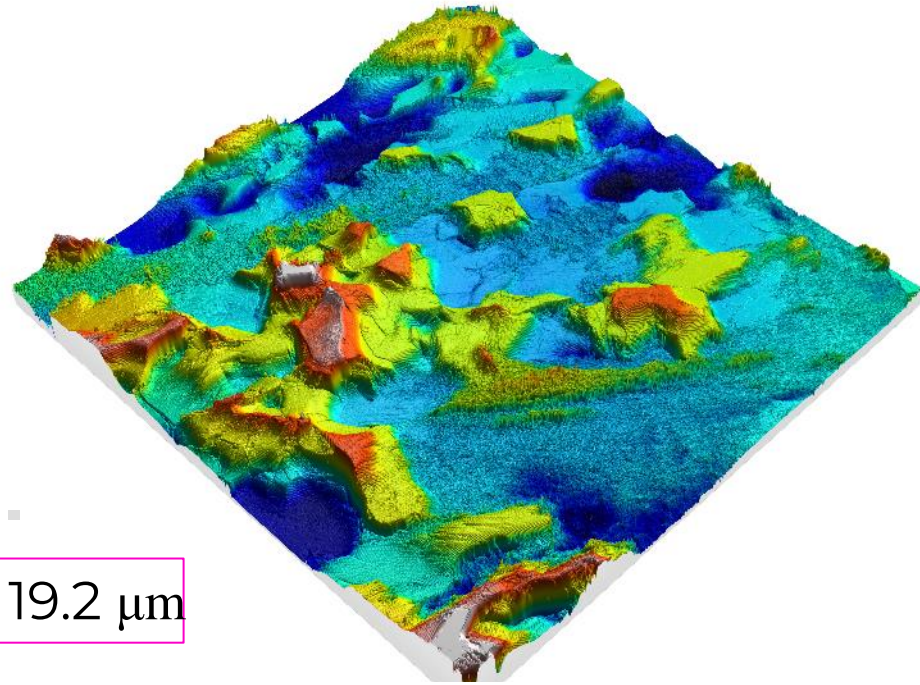
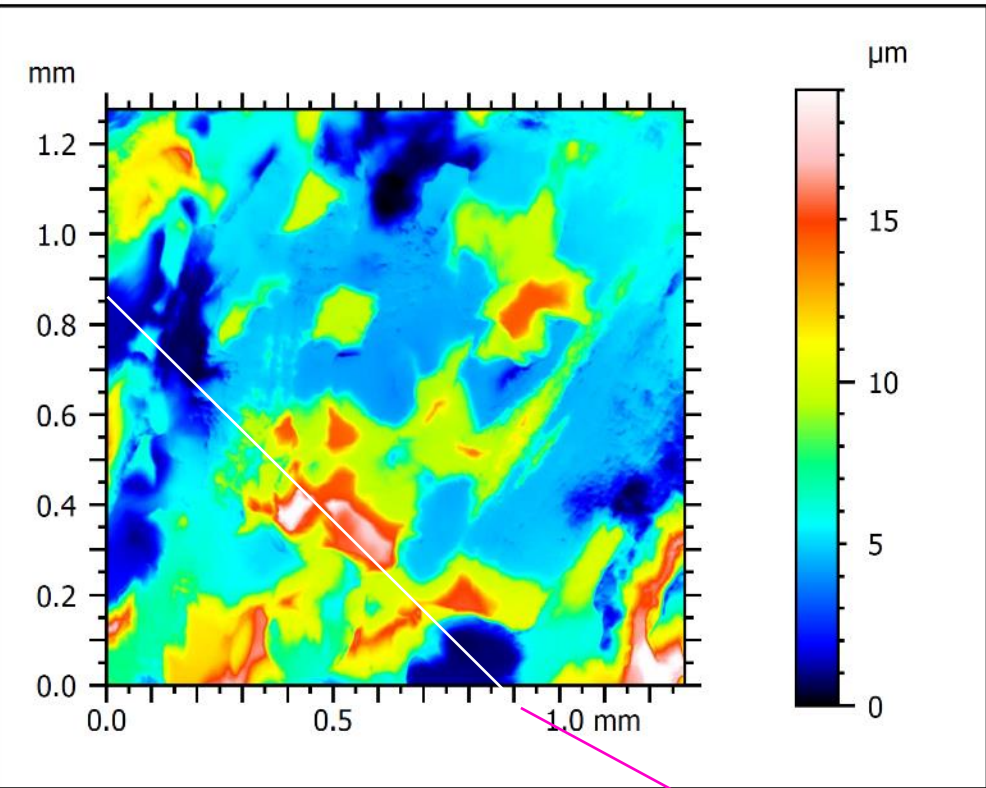
Optical (Polarized Light) Images



Laser Images

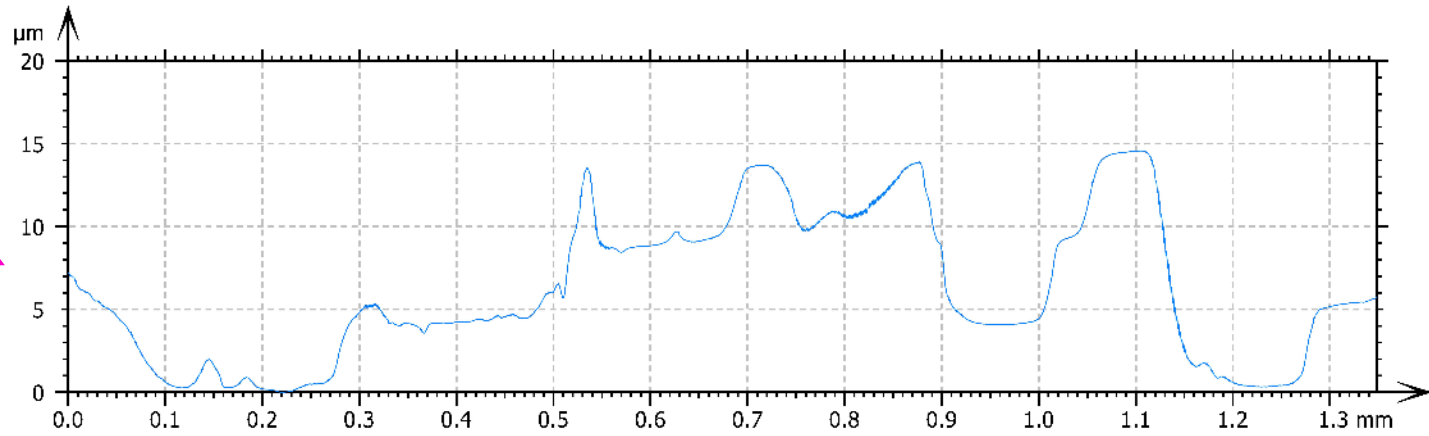


Surface Roughness



$S_z = 19.2 \mu\text{m}$

Height parameters		
Sq	3.508	μm
Ssk	0.8253	
Sku	3.602	
Sp	12.44	μm
Sv	6.598	μm
Sz	19.04	μm
Sa	2.784	μm



Parameters	Value	Unit
Length	1.348	mm

